

News Bulletin January 2011

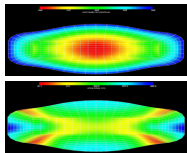
See You There...

SPIE
Photonics West

25 - 26 January 2011
The Moscone Center
San Francisco
California
USA

Moore Nanotech Booth #1338

Join us in San Francisco for the SPIE Photonics West Conference & Exhibition. We'll be exhibiting our latest Nanotech® 140GPM Glass Press Molding machine and GPMsim FEA software package. Practical product demonstrations will be provided, supported by our R&D/ Applications Specialist, David Adams.



Nanotech® 140GPM Glass Press Molding machine



For an insight into our broader product range and to learn more about how Moore Nanotech machine technology and knowhow can benefit your organization, we'll also have on hand Len Chaloux, Bob Cassin, Jeff Perra and Gavin Chapman.

Welcome on Board...

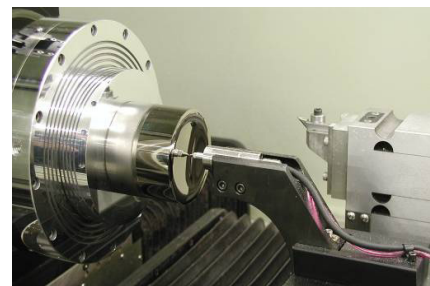
We are delighted to welcome Pat Hurst to the position of Engineering Manager. To many Pat will be a familiar face, indeed he was one of the very first employees at Moore Nanotechnology Systems when the business was formed



in 1997 and so played a key roll in our early product developments, including the Nanotech® 450UPL and 350FG machine platforms. Pat gained his Masters Degree in Mechanical Engineering under Professor Bob Hocken at UNC Charlotte, before settling in New Hampshire with his wife Kathy.

WECS On Machine Metrology...

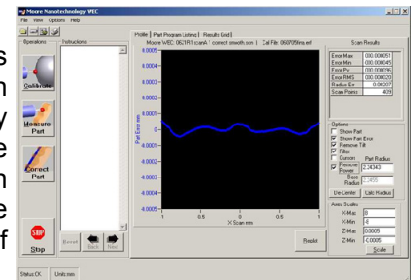
As a cost effective alternative to off-line and stand-alone form metrology, our Workpiece Measurement and Error Compensation System provides an effective means of measuring Aspheric form without removing the workpiece from the machine.



With options to measure only, or compensate residual errors, the system provides a large choice of options for filtering, excluding or expanding features or zones. Form errors, if repeatable, can easily be compensated in terms of both shape and power, with options that provide either partial or full compensation.

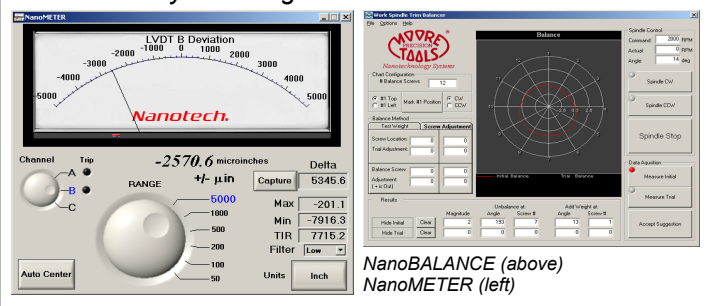
As with more traditional forms of Profilometry, WECS relies on careful calibration to establish the position of its Air Bearing LVDT Probe on the machine, and the circularity and size of the probe tip itself.

Independent comparisons have been made between WECS, Interferometry and Profilometry. These show excellent correlation in terms of quantitative errors and the details of those errors.



It's in the Details...

Quite apart from the core machines themselves, Moore Nanotech strives to achieve the ultimate 'user experience' by developing value-added features requested by you, the customer. Examples are our NanoBALANCE on-board spindle balancing software and our NanoMETER on-screen gage amplifier with true analog feel. We look forward to learning more about your wishes for future product developments and enhancements. *Please contact us and share your thoughts.*



NanoBALANCE (above)
NanoMETER (left)

Next Issue: Applications & After Sales Support